

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Züger  
SERIAL NO.: 10/530,994 GROUP NO.: 2823  
FILING DATE: April 12, 2005 EXAMINER: W. David Coleman  
TITLE: A Method For The Production Of A Substrate With A Magnetron  
Sputter Coating And Equipment For The Same

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

**COMMENT ON STATEMENT OF REASONS FOR ALLOWANCE**

In response to the Examiner's Statement of Reasons for Allowance, the Applicant submits that the prior art does not teach varying a total amount of material that is deposited on the substrate per time unit with a magnetron source that is phase-locked with the circular rotating of the magnetron magnetic field pattern.

Respectfully submitted,

Date: April 9, 2008

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